

PATENT
81848.0016.001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Chih-Chien Liu

Serial No: 09/546,174

Confirmation No.: 4793

Filed: April 11, 2000

For: HIGH DENSITY PLASMA
CHEMICAL VAPOR
DEPOSITION PROCESS

Art Unit: 1796

Examiner: Sergent, Rabon A.

**NOTICE OF APPEAL FROM THE PRIMARY
EXAMINER TO THE BOARD OF APPEALS**

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Applicant hereby appeals to the Board of Appeals from the office action dated March 13, 2008 of the Primary Examiner finally rejecting claims 50-69, 72, 74, 80-88 and 90-102. The item(s) checked below are appropriate:

1. A three-month extension of time to respond to the office action is hereby requested under 37 C.F.R. § 1.136 and is enclosed with the proper fee.
2. A timely response to the final rejection has been filed, as provided in 841 O.G. 1411.
3. The application is on behalf of
 - a small entity
Applicants claims small entity status.
 - other than a small entity.

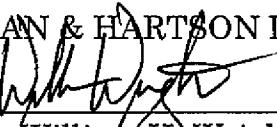
Fee \$255 \$510

- charge to Deposit Account No. 50-1314 the notice of appeal fee in the total amount of 510.00
- not required (fee paid in prior appeal); or
- charge to Deposit Account No. 50-1314 if any additional fees are required.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

By:


William H. Wright
Registration No. 36,312
Attorney for Applicant(s)

Date: June 13, 2008

1999 Avenue of the Stars, Suite 1400
Los Angeles, California 90067
Phone: 310-785-4600
Fax: 310-785-4601